

IN THE CLAIMS:

Cancel claims 1-20, without prejudice, and substitute  
therefor new claims 21-27, as follows:

*add*  
*a7*

21. (New) An apparatus for inspecting a substrate,  
comprising:

a substrate holder for holding a substrate to be inspected;  
an observation unit supporting section comprising a  
5 horizontal member that extends across the substrate holder and  
support columns that support the horizontal member at end  
portions thereof, said observation unit supporting section being  
movable along side edges of the substrate holder; and  
a micro observation unit that is movable in a direction in  
10 which the observation unit supporting section extends, and that  
scans a surface of the substrate.

22. (New) An apparatus for inspecting a substrate  
according to claim 21, wherein said substrate is a glass  
substrate, and said substrate holder comprises a hollow frame for  
sucking and holding a peripheral portion of the substrate holder.

23. (New) An apparatus for inspecting a substrate  
according to claim 21, wherein said micro observation unit  
comprises a visual inspection microscope including an objective  
lens and an ocular lens.

*a7*  
*Conceded* 24. (New) An apparatus for inspecting a substrate according to claim 21, wherein said micro observation unit comprises an image display device including a TV camera for imaging an object using an objective lens and a TV monitor for displaying an image.

25. (New) An apparatus for inspecting a substrate according to claim 21, wherein said observation unit supporting section is integrally provided with a transmission linear light source which is arranged at a level lower than that of the substrate holder and which extends in a direction in which the micro observation unit moves.

26. (New) An apparatus for inspecting a substrate according to claim 21, further comprising:

guide scales provided for the substrate holder and extending along adjacent sides of the substrate; and

a position coordinate detection section, movable along the guide scale, that detects a defect position coordinate based on two indices that intersect each other at a defect position on the surface of the substrate.

27. (New) An apparatus for inspecting a substrate according to claim 26, wherein each of said indices is a linear illumination index.